

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re U.S. Patent Application)
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Applicant: MAEDA et al.)
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Serial No.: Unassigned)
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Filed: April 26, 2005)
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For: METHOD FOR PRODUCING SILICON WAFER)
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PRELIMINARY AMENDMENT

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

Preliminary to the examination of the above application, please amend as follows: